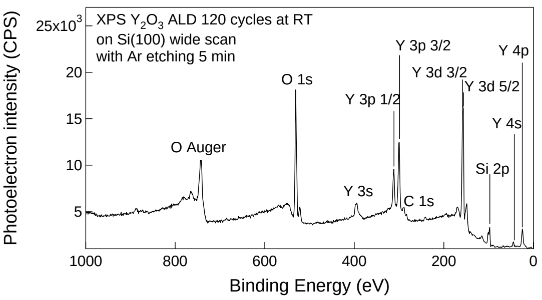

Fig.1 XPS wide scan spectrum obtained from the Y_2O_3 sample on Si.

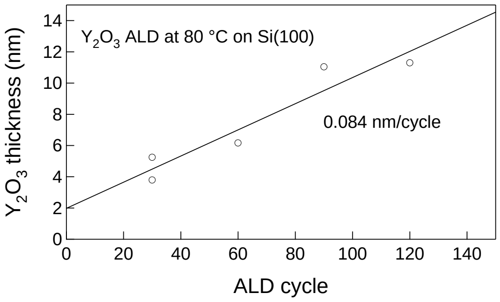

Fig.2 Y_2O_3 growth thicknesses as a function of the ALD cycle number.